

## **Overview of EUV Lithography at Carl Zeiss SMT: status and trends in optical coatings**

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In this presentation the current status of EUV optics development and manufacturing at Carl Zeiss SMT will be reviewed and an outlook on the EUV optics roadmap will be given.

After delivery of the optical trains for ASML's Alpha DemoTools in 2005/06, Carl Zeiss SMT has shipped in 2009/10 the illumination and projection Optics for ASML's NXE:3100 systems. In 2010 the production of optics with improved specifications for the next generation of EUVL tools with a numerical aperture of beyond 0.3 was started. In addition, a new illumination system has been developed. We will report on the status and trends in optical coatings at Carl Zeiss SMT GmbH.